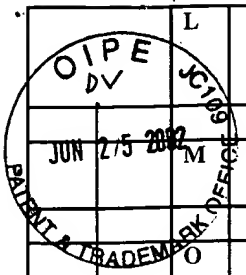
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OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)										
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